



PATENT APPLICATION

ITW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kenichi SHIRAISHI



Group Art Unit: 2852

Application No.: 10/588,146

Filed: November 6, 2006

Docket No.: 128985

For: EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD, MAINTENANCE METHOD, AND EXPOSURE METHOD

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. One or more reference cited herein was cited in a counterpart foreign application. An English language version of the foreign search report is attached for the Examiner's information. See References 1-2.
- ☒ 3. In accordance with 37 CFR §1.98(a)(2)(ii), copies of any U.S. patents and patent application publications are not attached.

Respectfully submitted,


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MAC:JEG/pdw
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